

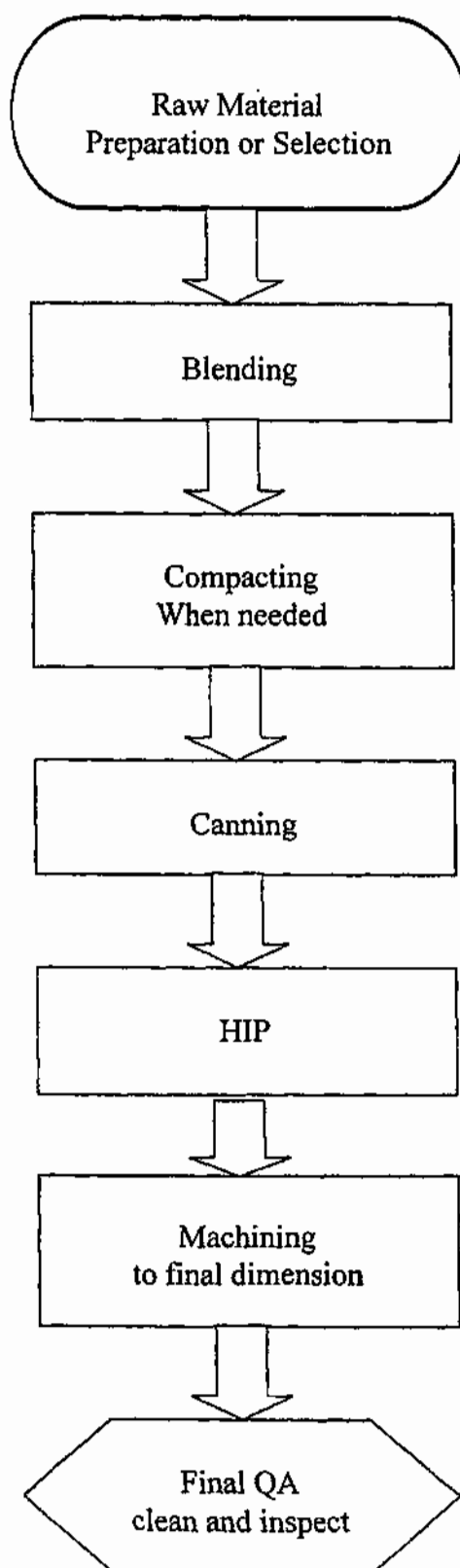


Figure 1. Process Flow Chart for the Production of B/C/N/O/Si Doped Sputtering Targets